

*IN THE UNITED STATES PATENT AND TRADEMARK OFFICE*

In re Patent Application of :  
Ju-Cheol SHIN et al. : Attn: Applications Branch  
Serial No. (New) : Attorney Docket No. SEC.828D  
Filed: June 24, 2003 :  
For: CHEMICAL VAPOR DEPOSITION METHOD FOR DEPOSITING  
SILICIDE AND APPARATUS FOR PERFORMING THE SAME

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Honorable Commissioner For Patents  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Sir:

Preliminary to the examination of the above-identified application, the  
following amendments and remarks are submitted:

In the Specification

***Kindly add the following new section between lines 2 and 3 at page 1 of the  
specification:***

**CROSS-REFERENCE TO RELATED APPLICATIONS**

This is a divisional of Application Serial No. 09/884,993, filed June 21, 2001,  
which is incorporated herein by reference in its entirety.